

Longitudinal manipulations with intensity effects in SIS-100



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Outline

- Introduction
- Choice of key parameters: rf voltage ramps, phases and merging time
- Intensity effects: Longitudinal space charge and cavity beam loading
- Simulation of longitudinal manipulation of proton bunches with optimized parameters (two examples)
- Simulation of heavy ion (U^{28+}) bunch manipulation including fast bunch rotation with optimized parameters
- Summary



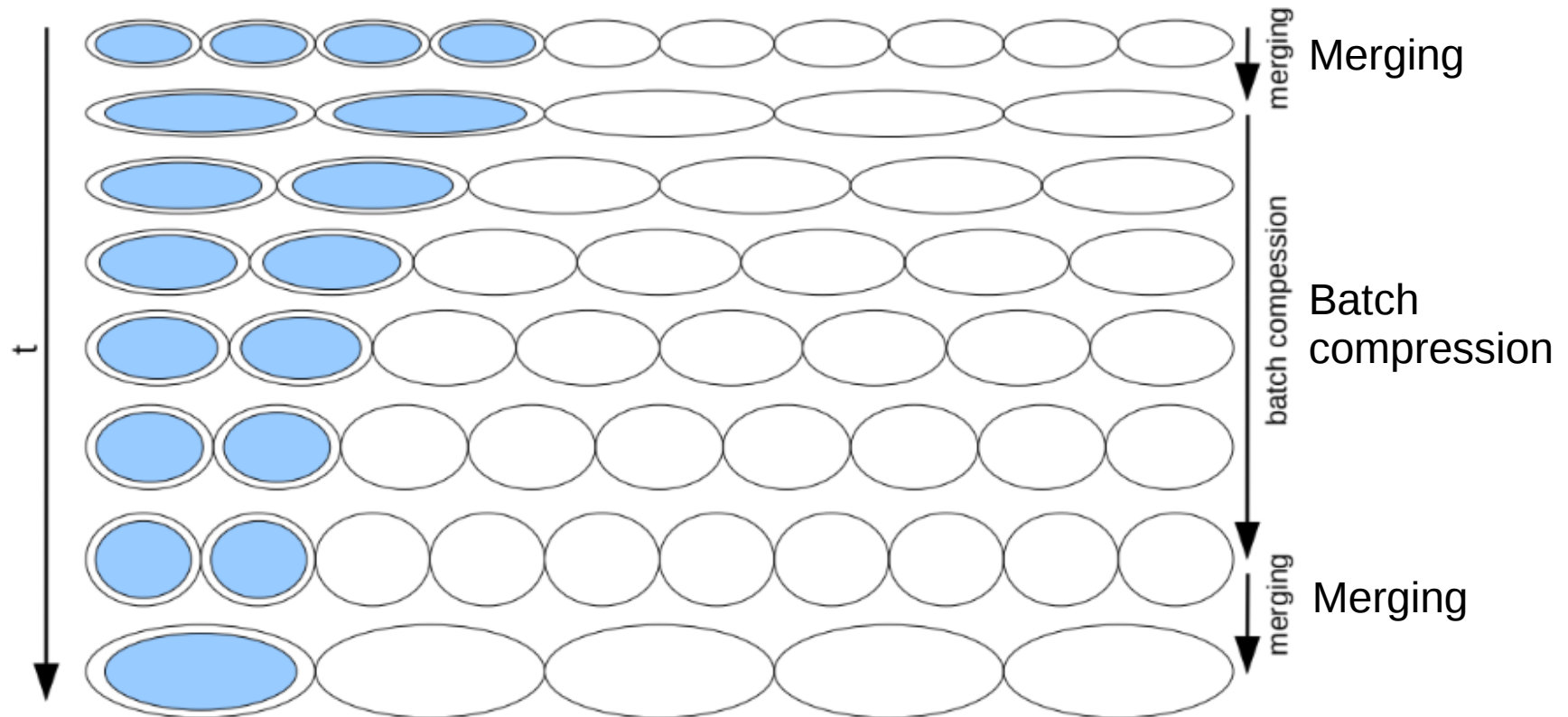
Introduction

- In SIS-100, for proton operation, four bunches are merged to one bunch:

1) First merging: 4 bunches ($h=10$) \longrightarrow 2 bunches ($h=5$)

2) Batch compression: 2 bunches compressed ($h=5$ to 10)

3) Second merging: 2 bunches ($h=10$) \longrightarrow 1 bunch ($h=5$)



Choice of key parameters

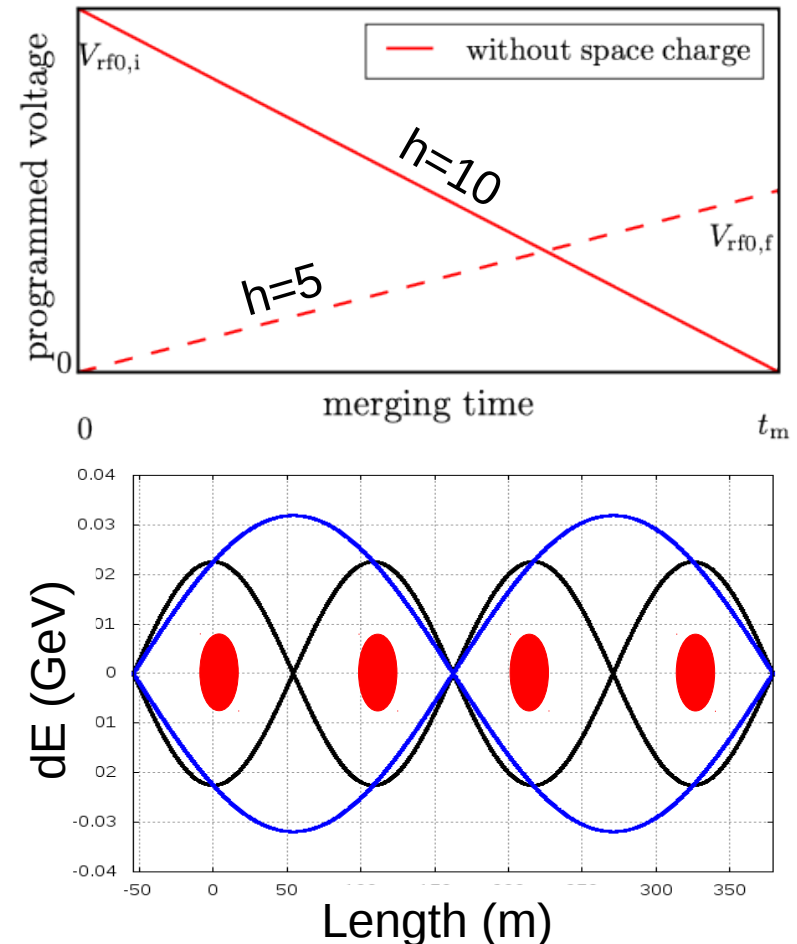
- Bunch merging with constant bunching factor

→ Bunching factor defined as $B_f = \frac{\text{bunch length}}{\text{bucket length}}$

{ Longitudinal emittance $\epsilon_{L,f} = 2\epsilon_{L,i}$
 Bunch length $\hat{l}_f = 2\hat{l}_i$
 Momentum spread $\hat{\delta}_f = \hat{\delta}_i$

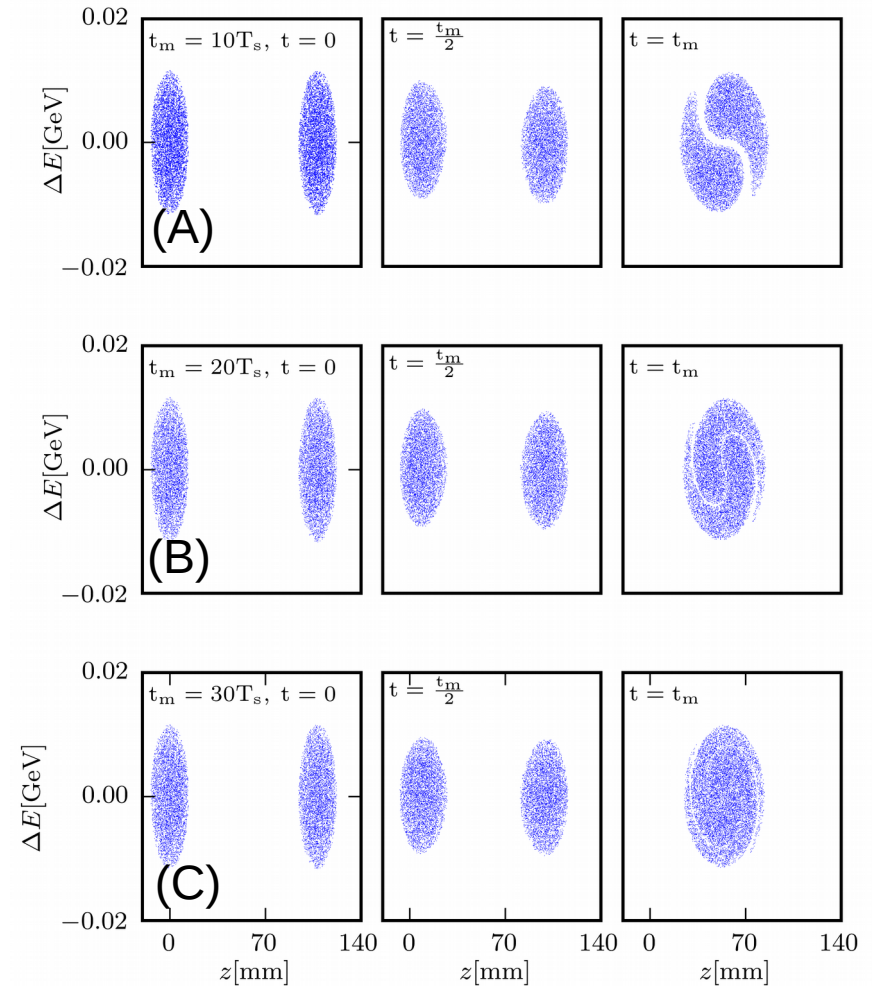
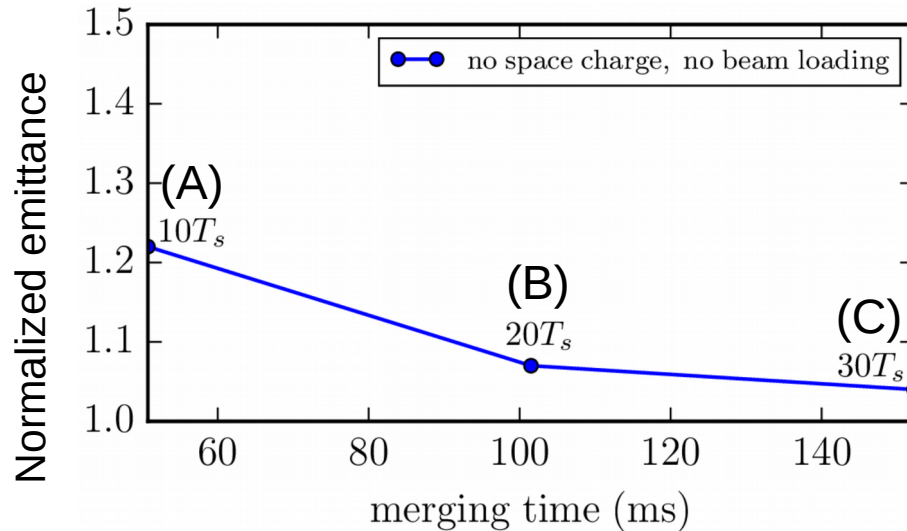
→ Matched RF voltage $V_{\text{rf},i} = 2V_{\text{rf},f} = 66\text{kV}$

→ RF phase $\phi_1 = 0, \phi_2 = 90^\circ$



Choice of parameters for bunch merging

- Merging time can be determined via simulation results
 - ~100 ms (20Ts) can ensure a good emittance conservation

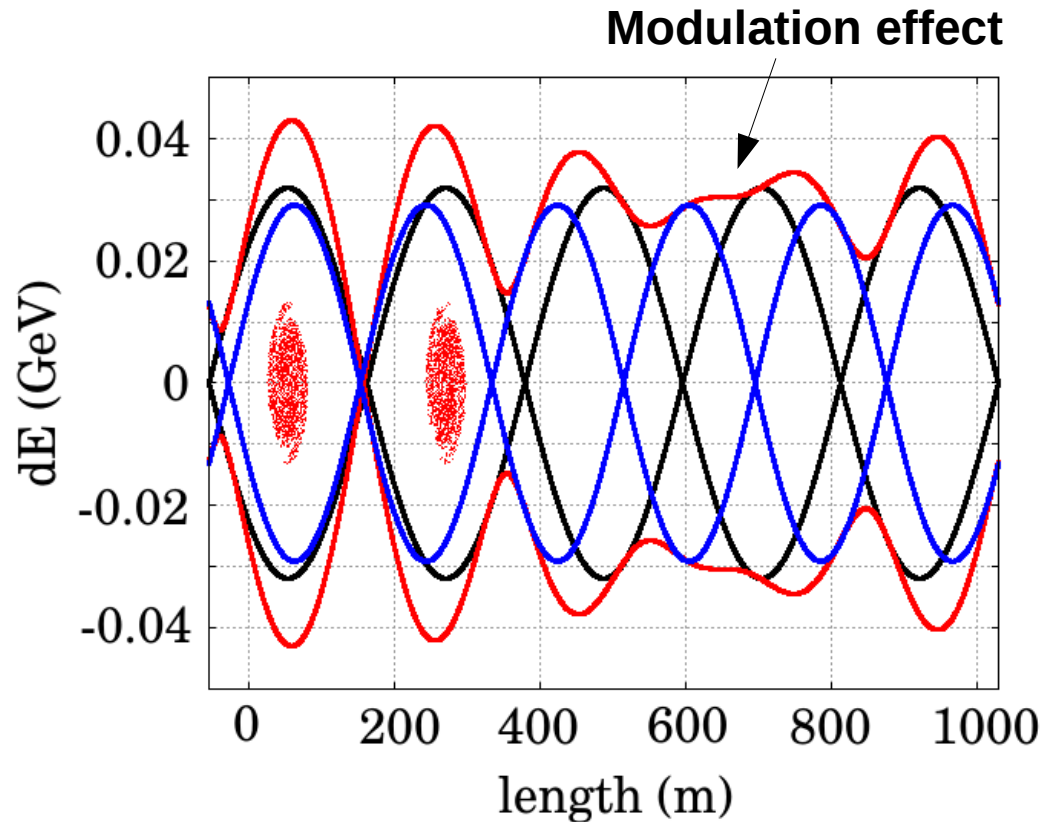


Case	Synchrotron period (T_s)	Turns (n)	time (t_m , ms)
A	10	6650	50.8
B	20	13300	101.6
C	30	26600	203.2

pyORBIT is employed for the simulation

Choice of parameters for batch compression

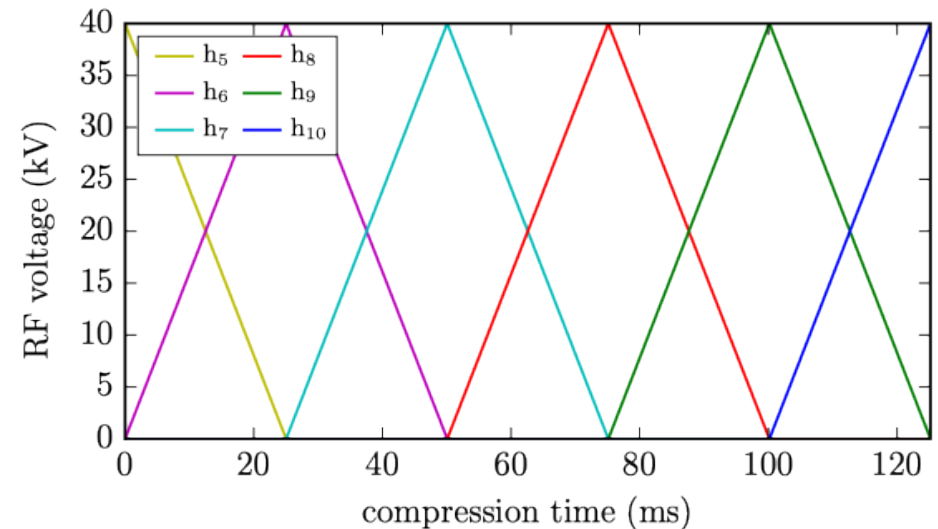
- For short bunch train, modulation effect is not a problem



Batch compression with harmonics on $h = 5$ and $h = 6$ (at $V_5 = V_6$)

Black $h=5$; Blue $h=6$; Red combined

- The emittance growth is less sensitive to the rf voltage than during bunch merging. Equal voltage amplitude on harmonic is chosen.



rf voltage ramps for batch compression

Intensity effects – longitudinal space charge

- Space charge can be well-compensated via increasing external rf voltage

- Space charge parameter $\Sigma_{sc} = \frac{V_{sc}}{V_{rf}}$

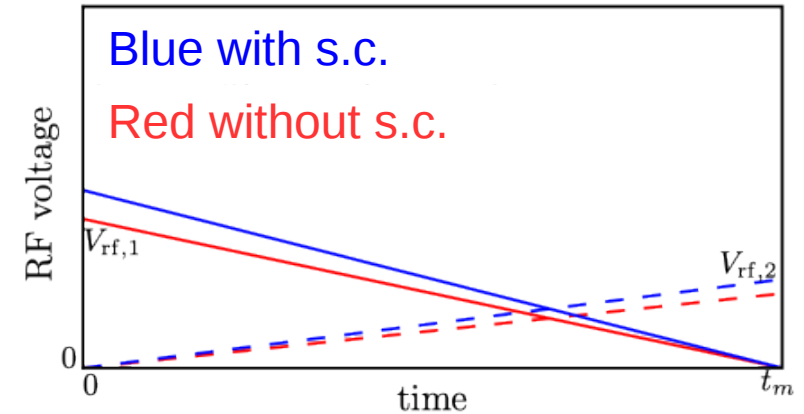
→ e.g. For bunch merging on SIS-100,
(rms emittance $6.26 \text{ m} \times 0.0011$)

$$V_{rf,sc,i} = 66.0 + \boxed{12.7} = 78.7 \text{ kV}$$

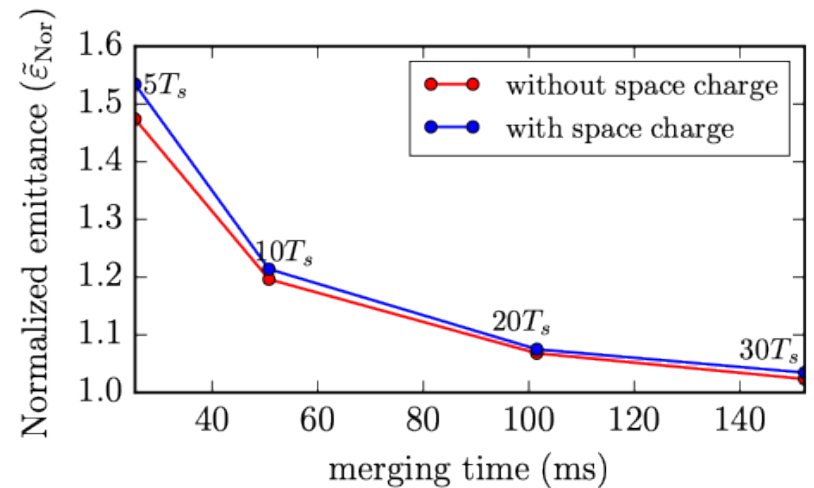
s.c.voltage

$$V_{rf,sc,f} = 33.0 + \boxed{6.3} = 39.3 \text{ kV}$$

$$\Sigma_{sc} = 0.19$$



Matched rf voltage ramps without/with s.c.



Final emittance under different merging time without/with s.c.

Intensity effects – cavity beam loading

- Beam loading can be evaluated by RLC model
 - e.g. Initial beam loading voltage of four bunches on SIS-100,
 $V_{bl0} = 7.61, 9.79, 15.1, 16.2$ kV

- Beam loading matching shifts

$$\Delta\phi_{bl} = a \sin\left(\frac{V_{bl0}}{V_{rf0}}\right)$$

- Beam loading parameter

$$\Sigma_{bl} = \frac{V_{bl0}}{V_{rf0}}$$

to evaluate the contribution of the beam loading

Parameters [unit]	Symbols	Initial value
Resistance [Ω]	R_{sh}	2000
Resonant freq. [Mhz] on h=10	$f_{res,h=10}$	2.72
Resonant freq. [Mhz] on h=5	$f_{res,h=5}$	1.36
Quality factor on h=10	$Q_{h=10}$	10.6
Quality factor on h=5	$Q_{h=5}$	5.3

Beam loading parameters in SIS-100

- The cavity number should be as few as possible to minimize the beam loading effect

Bunch merging with intensity effects

- Choice of merging time

→ Longer merging time

Better merged

Longer beam loading effect

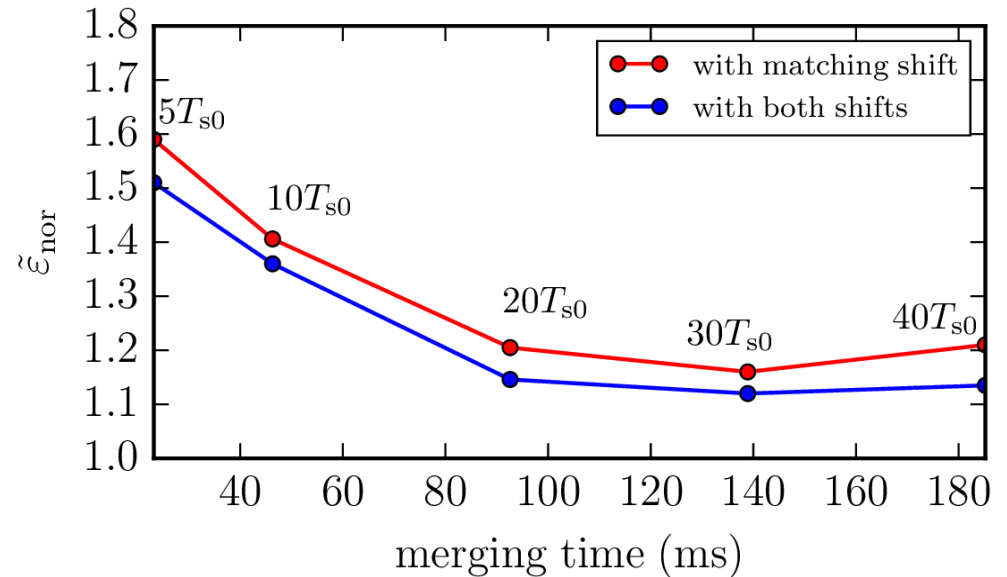
→ Preferred: **100 ms**

- Two beam loading compensation shifts

→ “Matching shift” for initial matching

$$\Delta\phi_{bl} = a \sin\left(\frac{V_{bl0}}{V_{rf0}}\right) = a \sin(\Sigma_{bl})$$

→ “Symmetry shift” for keeping the merging to be symmetrical



Final emittance growth with beam loading and space charge

Red: with initial matching shift

Blue: with both shifts (reduced emittance)

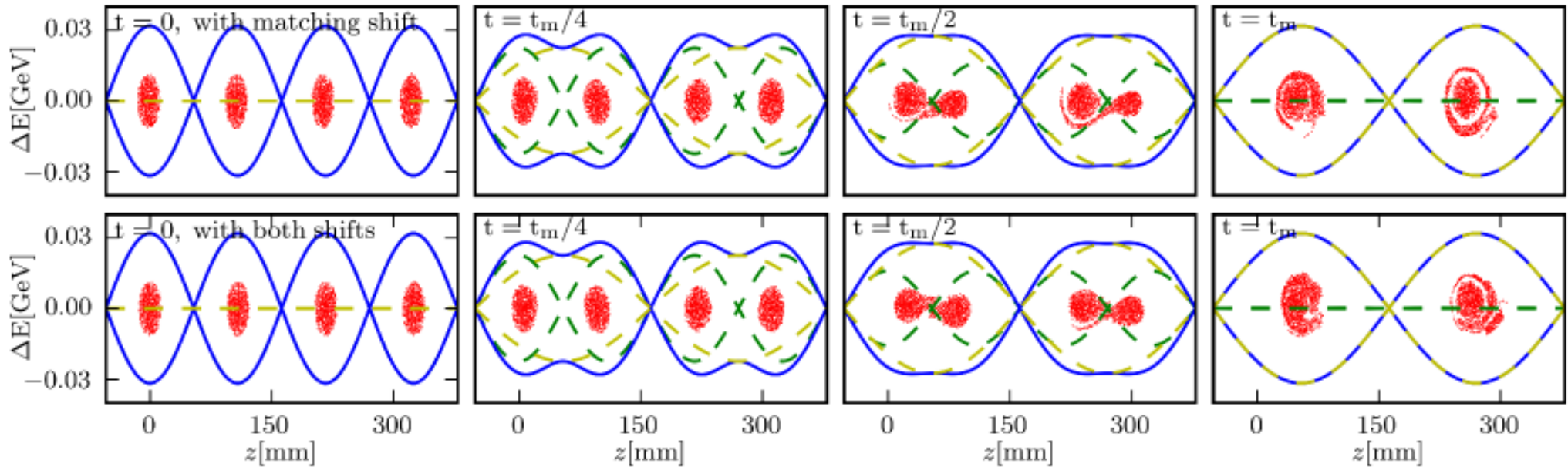
$$\Delta\phi_h = \frac{1}{n_b} \sum_{j=1}^{n_b} \Delta\phi_{bl,j}$$

(A physics paper to be submitted.)



Bunch merging with intensity effects

- Simulation results



Upper: with matching shift

Lower: with both shifts

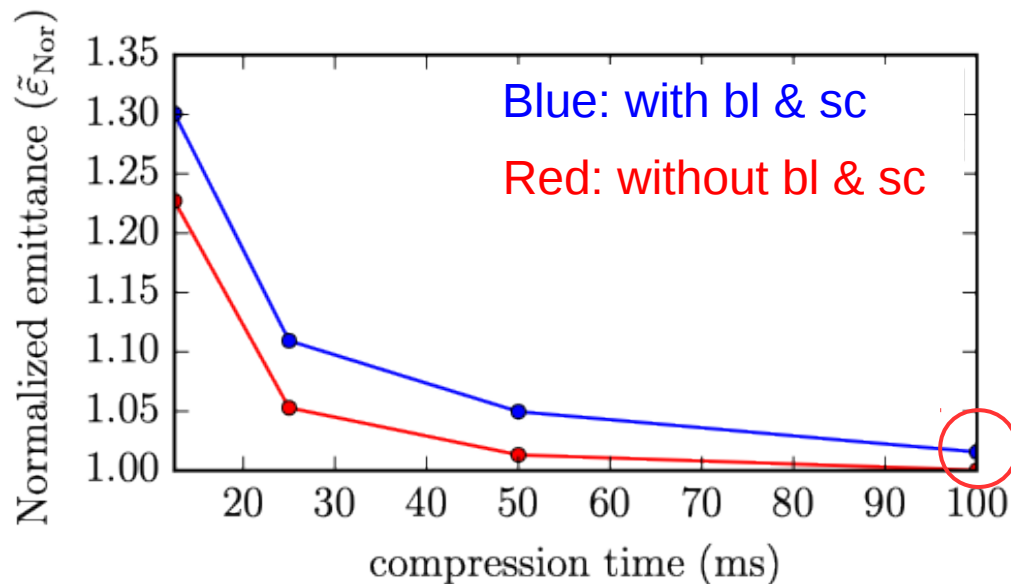
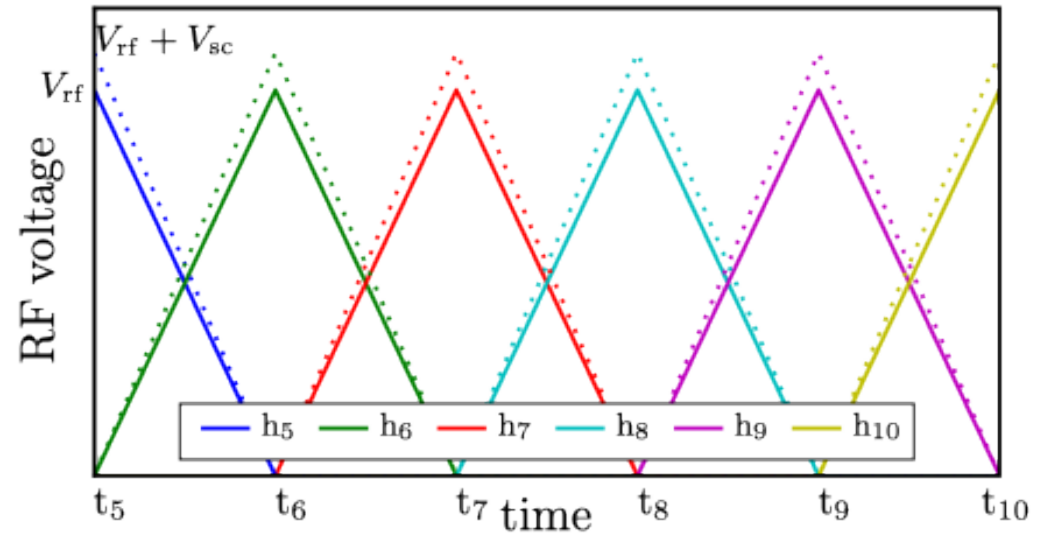
- The emittance growth reduces with the symmetry shift.
- Merging time: 100 ms

Batch compression with intensity effects

Rf voltage ramps with space charge matching for batch compression

$V_{rf} = 33 \text{ kV}$ Solid line

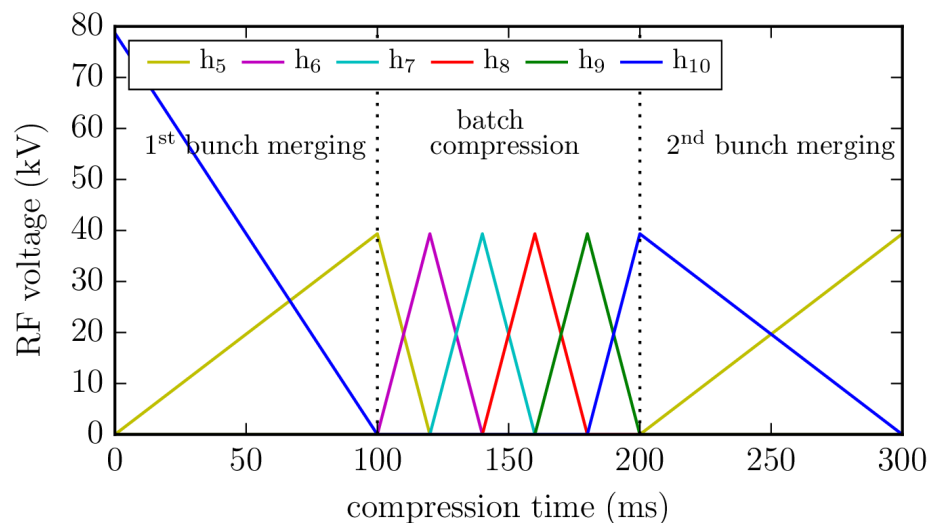
$V_{rf,sc} = 39.4 \text{ kV}$ Dashed line



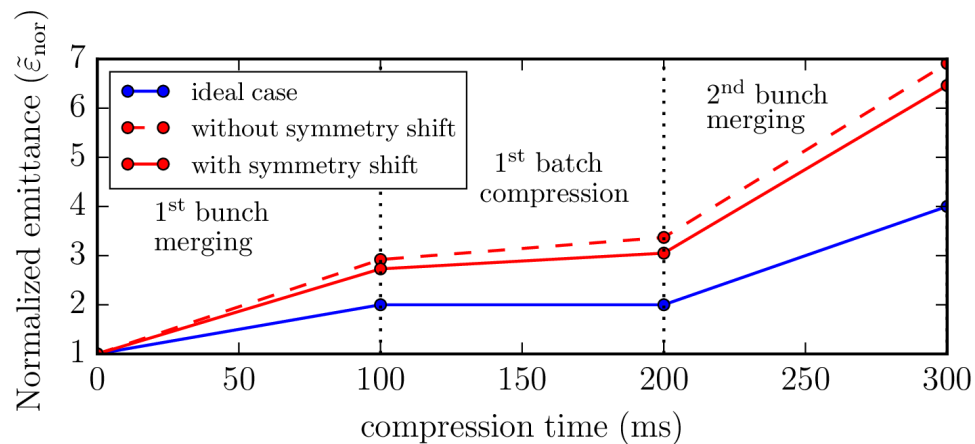
Emittance growth with different compression time

- During batch compression the beam loading effect is weaker (~2% emittance growth) than in bunch merging (~ 20%)

An example of proton bunch manipulation



Example rf voltage amplitude ramps



Emittance growth

Red: with both compensation shifts Dashed red: without symmetry shift
 Blue: ideal case

Parameters [unit]	Initial value	End of first merging	End of batch compression	End of second merging
Total emittance growth	-	36.5%	44%	59%
Bunching factor	0.18	0.21	0.34	0.37
rms bunch length [m]	6.25(*4)	13.4, 14.1	12.1, 13.9	23.5
rms momentum spread($\times 10^{-3}$)	1.11(*4)	1.31, 1.42	1.52, 1.58	1.89



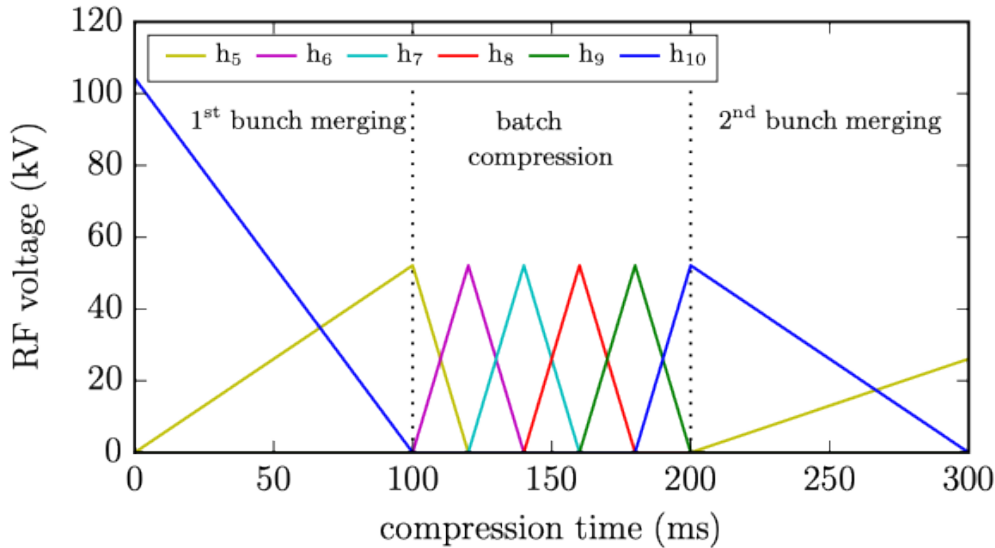
An example of proton bunch manipulation

Parameters [unit]	Initial	End of first merging	End of batch compression	End of second merging
rf voltage [kV]	78.7	39.35	39.35	39.35
Harmonic number	10	5	10	5
Bare synchrotron tune [$\times 10^{-4}$]	8.0	4.0	5.6	4.0
Compression time[ms]	-	100	100	100
Phase on h_{10}	0	0	180+180	0
Phase on h_9	-	-	144+162	-
Phase on h_8	-	-	108+144	-
Phase on h_7	-	-	72+126	-
Phase on h_6	-	-	36+108	-
Phase on h_5	90+4.2	0	0+90	90
Cavity numbers	8	8	6	6

Main parameters for the proton bunch manipulation



Second example of proton bunch manipulation



← Proposed rf voltage ramps for the second case.

Doubled emittance

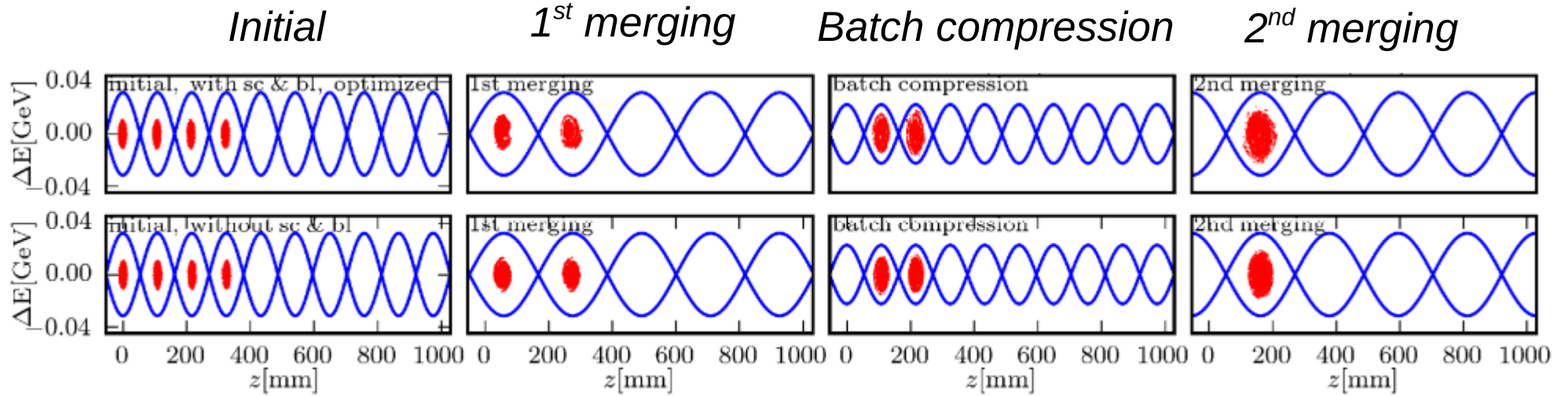
Reference emittance

Comparison of the parameters in two examples →

Parameters [unit]	First example	Second example
Initial rms bunch length [m]	6.25	4.42
Initial rms dp_p [10 ⁻³]	1.11	0.78
Matched Voltage [kV]	78.7	104.3
beam loading voltage [kV]	12.2	20.6
Space charge voltage [kV]	12.7	38.3
Σ_{sc}	0.192	0.58
Σ_{bl}	0.154	0.197

Second example of proton bunch manipulation

- Simulation result



Particle distribution in the phase space during bunch manipulation

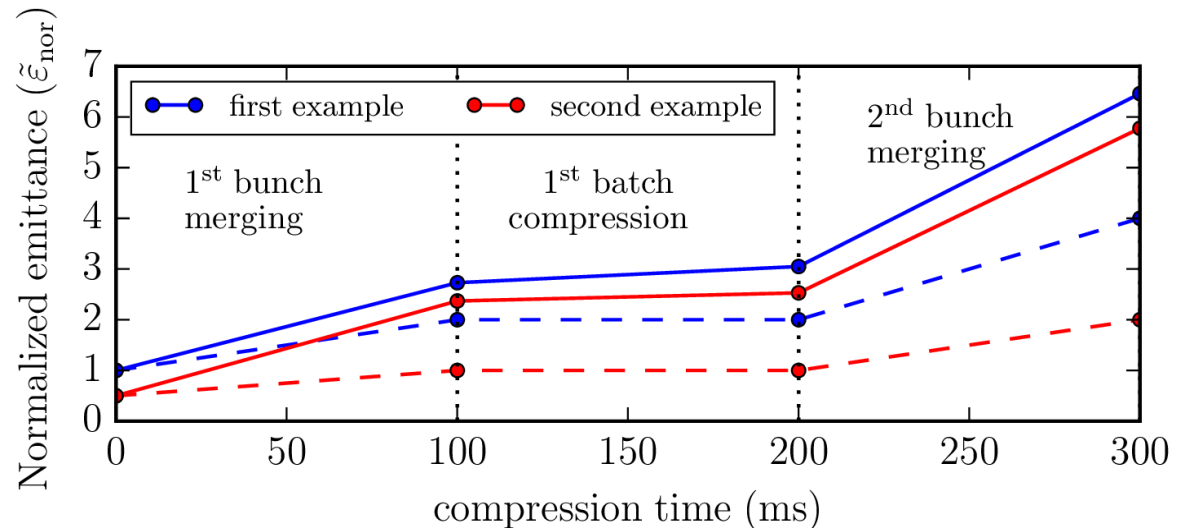
Red: Second example

Blue: First example

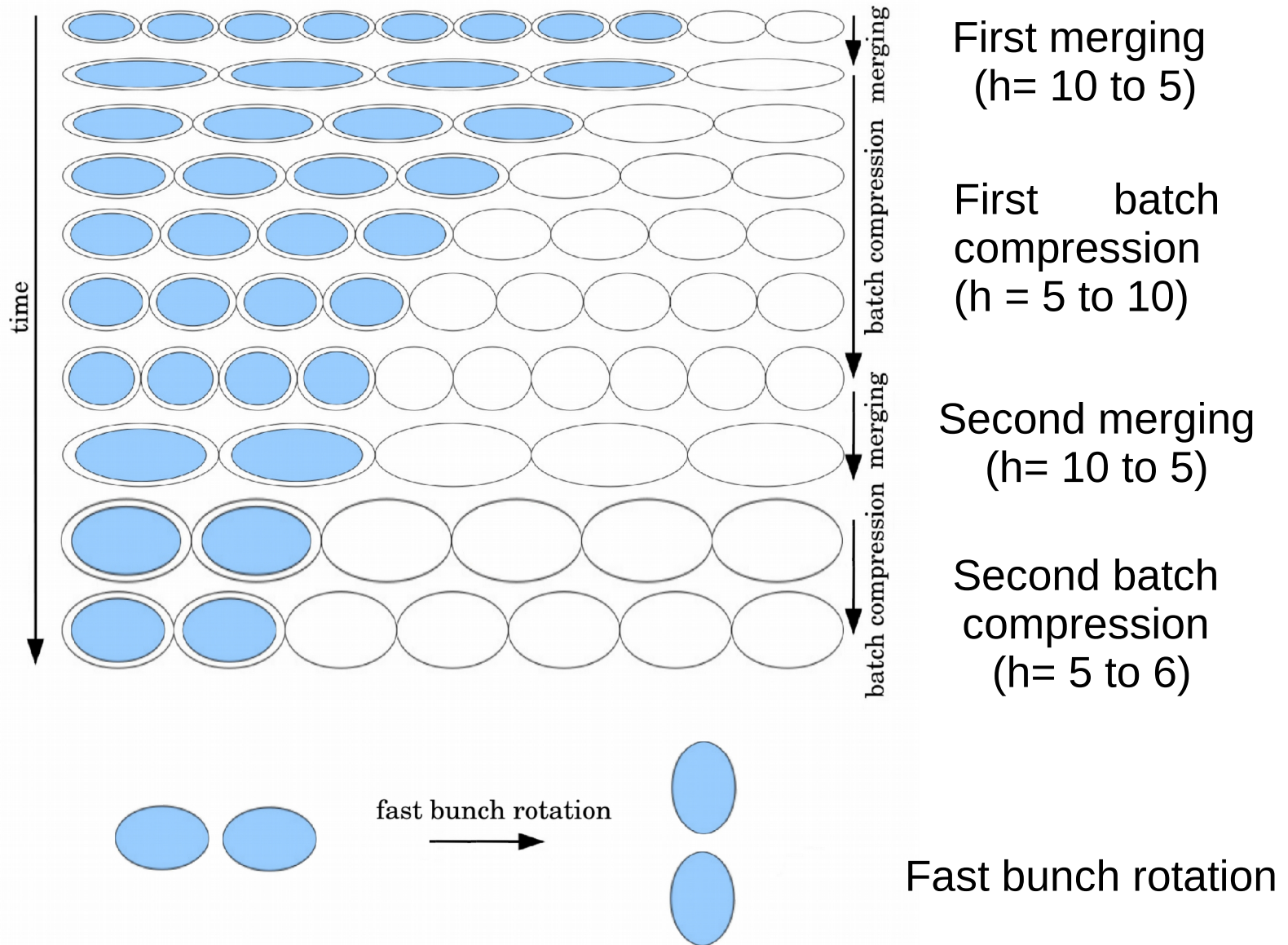
Dashed line: ideal case

Solid line: with intensity effects

- The emittance growth is not sensitive to the initial emittance



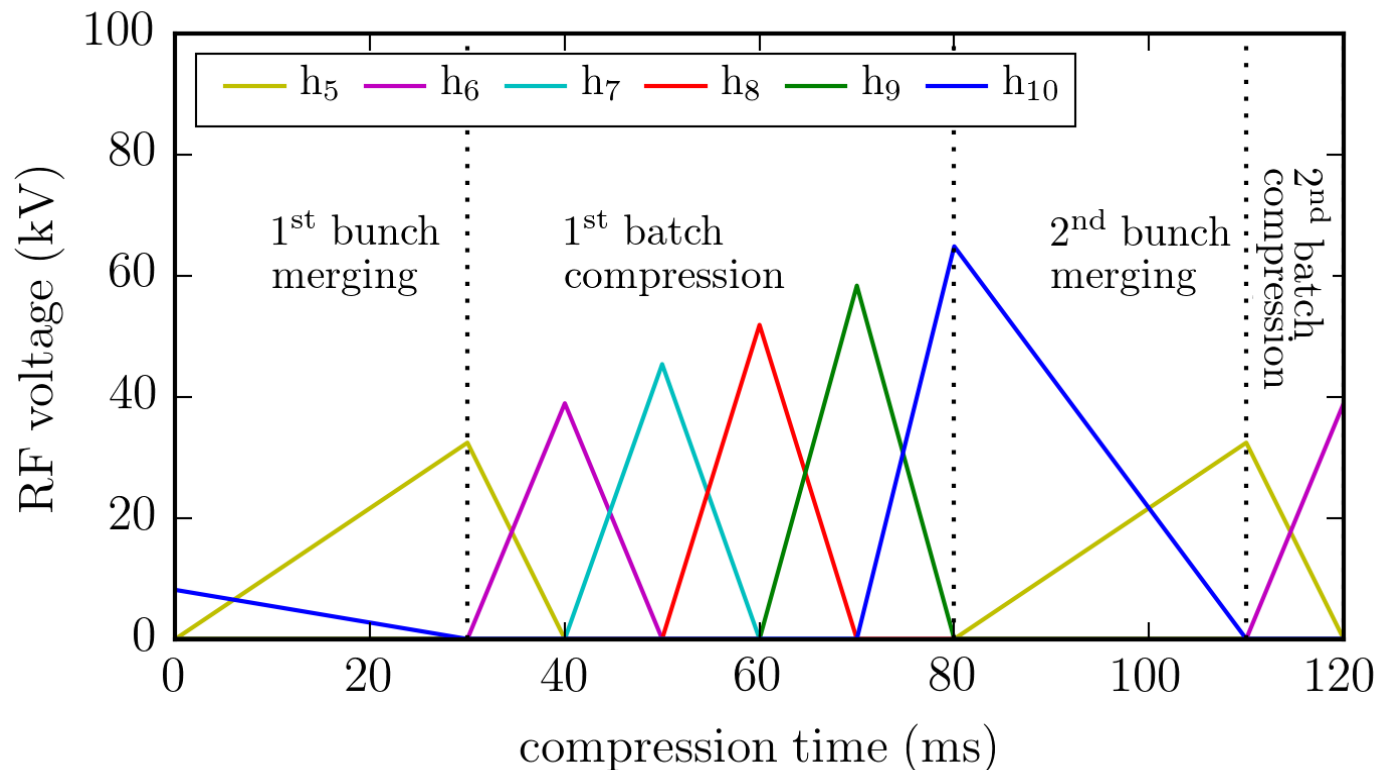
Proposed schemes for heavy ion (U^{28+}) bunch manipulation



Proposed heavy ion manipulation scenario after optimization

Proposed rf voltage ramps for heavy ion manipulation

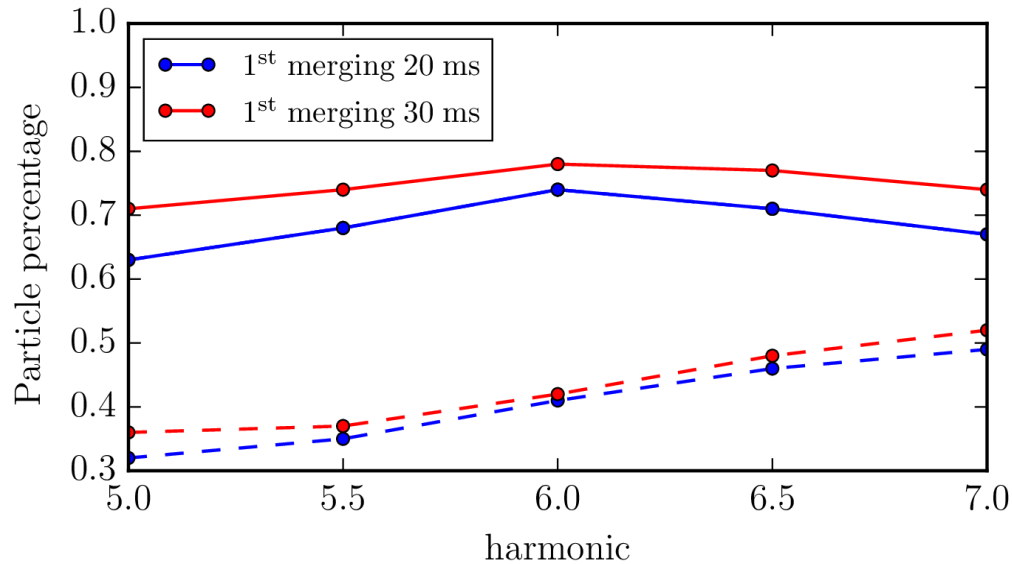
- For 1st merging and batch compression: voltages in h=5 increase fast to provide a large bucket area (acceptance).
- For 2nd merging, voltages in h=5 halved to generate a longer bunch length
- For 2nd batch compression h=5 to 6, distance decreased



Design of fast bunch rotation

- Large distance leads to large filamentation (limited voltage 360 kV)

→ Rotation of two bunches after batch compression



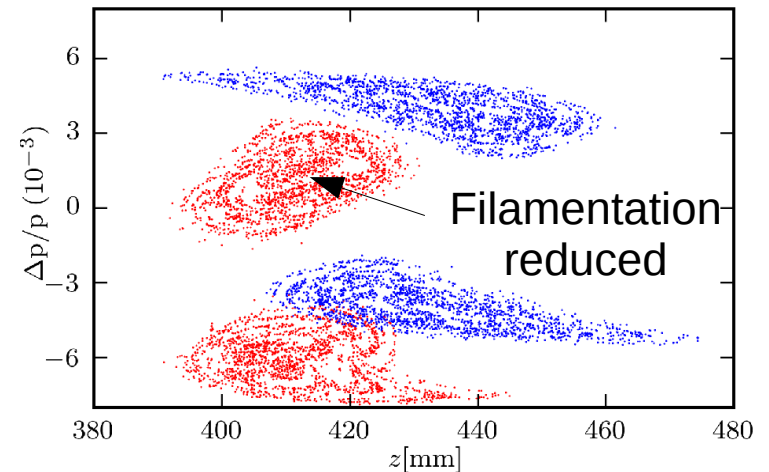
- Beam loading can dampen the filamentation

→ Beneficial effects

(Deserves a further study)

Parameter [unit]	Symbol	Value
Q-factor	Q	2
Shunt impedance [Ohm]	R_{sh}	1000
Cavity number	n_{cav}	9
Maximum voltage [kV]	V_{rf}	40
Harmonic	h	2
Rotation voltage	$V_{rotation}$	360

Model of bunch compression cavity



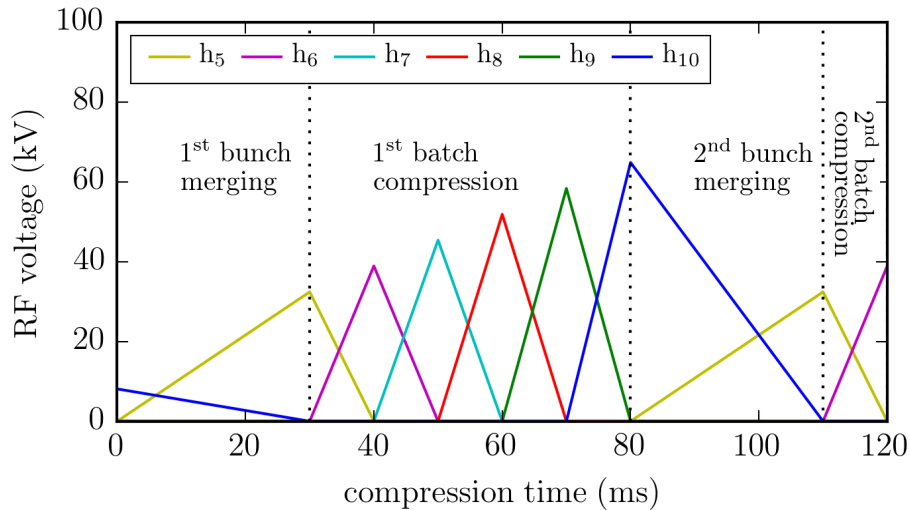
Design of fast 90° bunch rotation

- Main parameters for the fast bunch rotation

Parameters [unit]	Initial	1 st bunch merging	1 st batch compression	2 nd bunch merging	2 nd batch compression	Fast rotation
rf voltage [kV]	8.1	32.4	64.8	32.4	38.9	360.0
harmonic	10	5	10	5	6	2
cavity numbers	3	3	5	5	4	9
rms bunch length [m]	11.6	25.6	21.4	25.3	24.2	6.1
rms momentum spread [$\times 10^{-4}$]	1.1	1.4	2.0	3.3	4.1	37.5

More detailed parameters can be found in the technical report

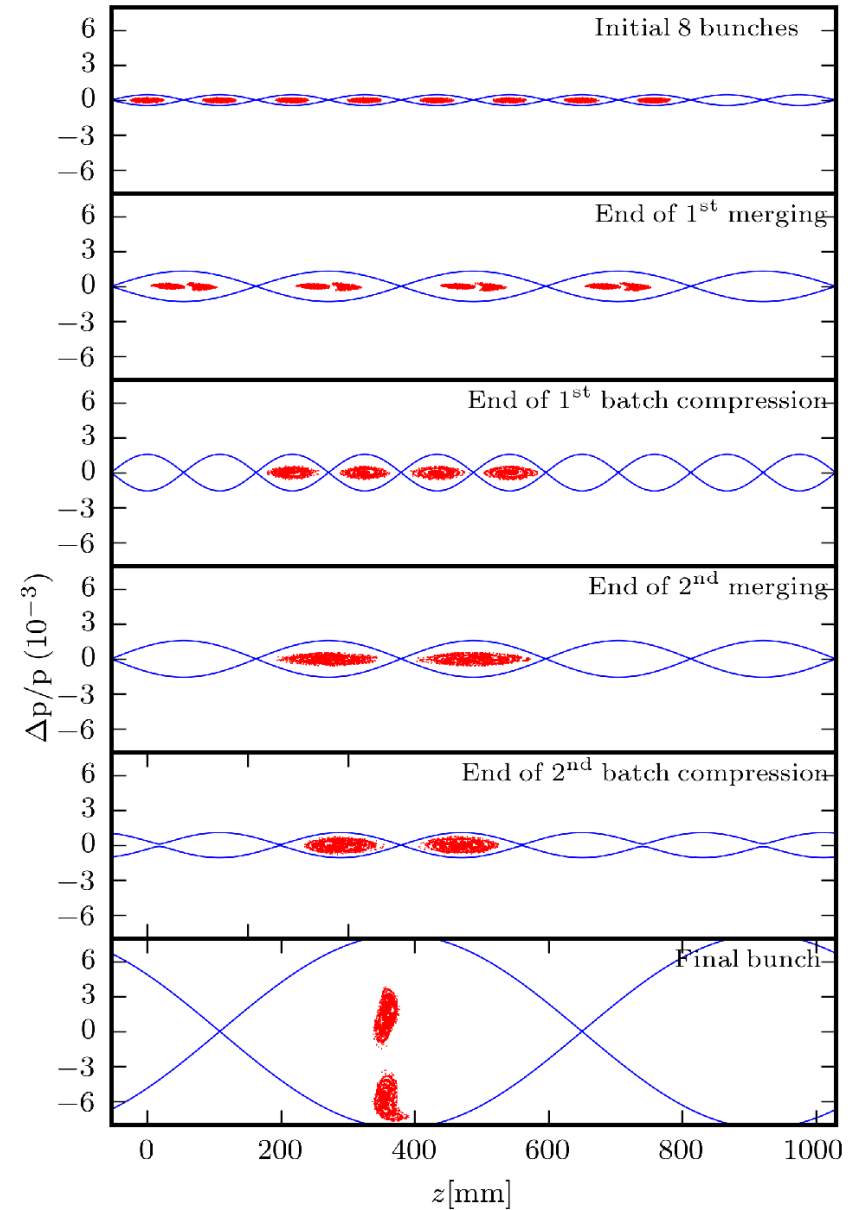
Simulation results of fast bunch rotation



Parameters [unit]	Value
particle percentage within 70 ns window	87%
(2 σ) bunch length [m] (target / simulation)	9.7 / 8.74
(2 σ) momentum spread (target / simulation)	5×10^{-3} / 3.75×10^{-3}

Designed final bunch parameters

An important criteria: compression time as short as possible



Summary

- Longitudinal bunch manipulation (bunch merging and batch compression) in SIS-100 including high intensity effect are investigated.
- Bunch merging scenario with tolerable emittance growth are demonstrated
- Manipulation of four proton bunches towards a single bunch in SIS-100 is shown, using an example ramp.
- Manipulations of eight U28+ bunches towards a single bunch, including fast bunch rotation: an optimized scenario to meet the user requirements
- Optimized ramp parameters are used to minimize the emittance growth caused by intensity effects.

The report available at <https://repository.gsi.de/record/238378>



Thanks for your attention!



Appendix I Space charge calculation (Elliptical model)

- Space charge voltage is calculated based on the **elliptical model**

- Elliptical model

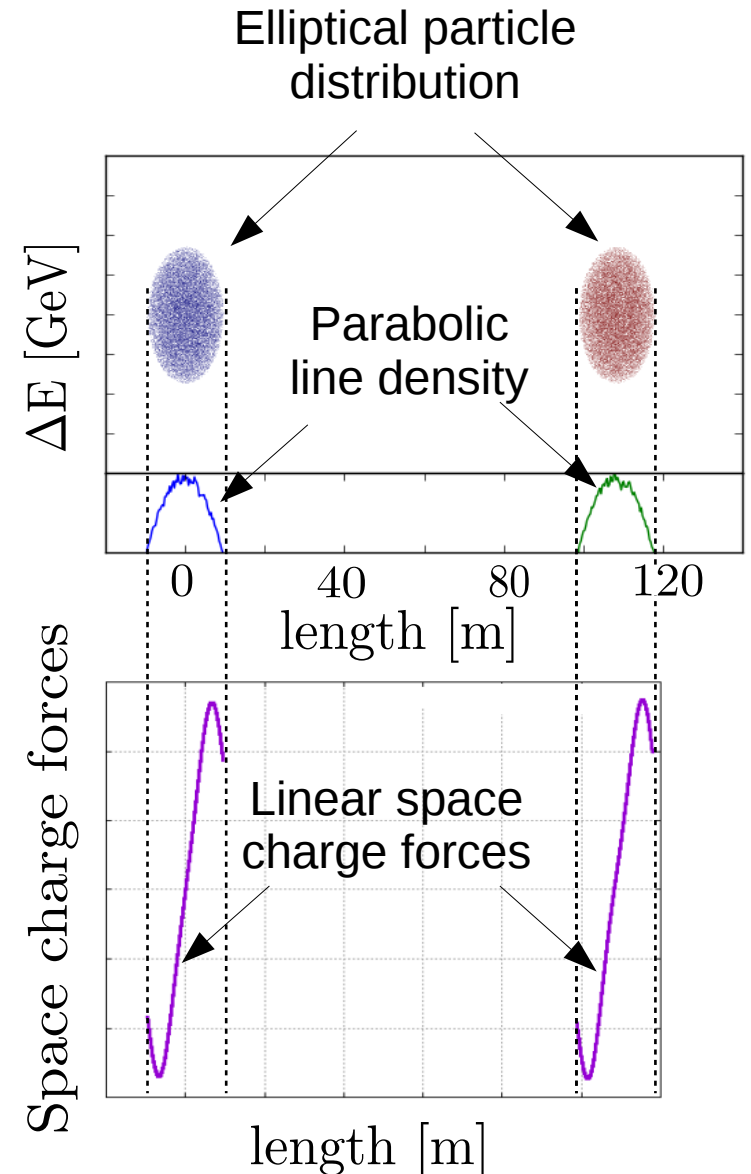


Parabolic line density



Linear space charge forces

- With space charge, the rf voltage should be increased to compensate the space charge defocusing force (voltage)



Appendix II Beam loading calculation model

- The parallel RLC circuit seen by the beam

→ Cavity impedance

$$Z_{bl}(\omega) = \frac{R_{sh}}{1 + iQ_c(\omega/\omega_r - \omega_r/\omega)}.$$

Shunt impedance

Q-value Resonant frequency

→ Beam loading
Induced-voltage

$$V_{bl}(z) = - \sum_{n=0}^{\infty} I_n Z_n e^{inz/R}$$

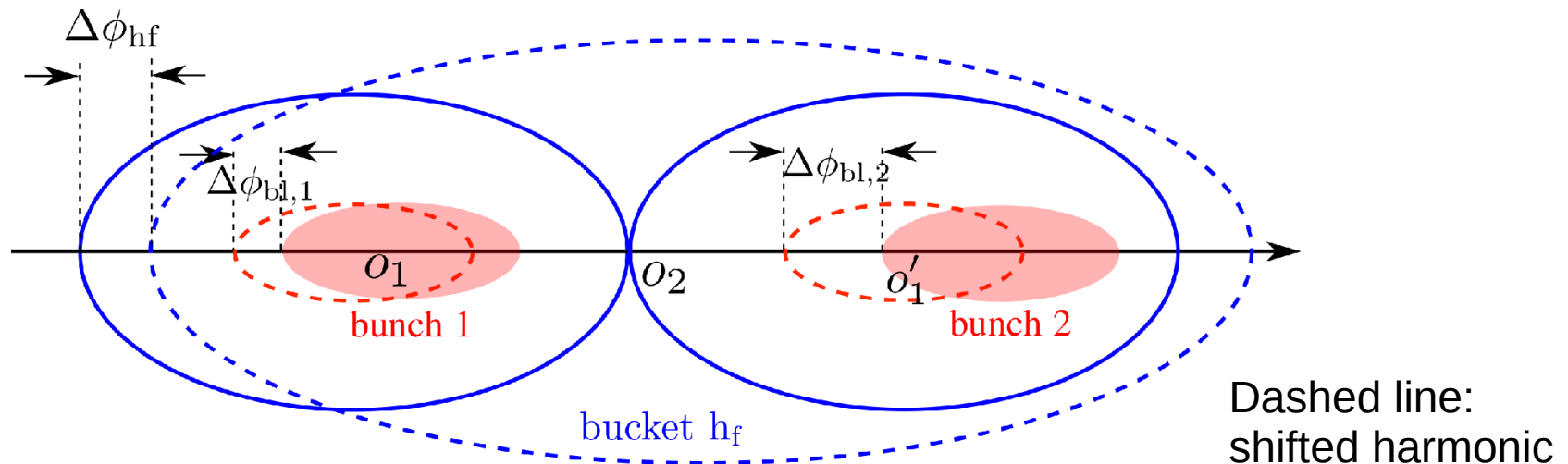
beam current
spectrum

Appendix III Beam loading shifts

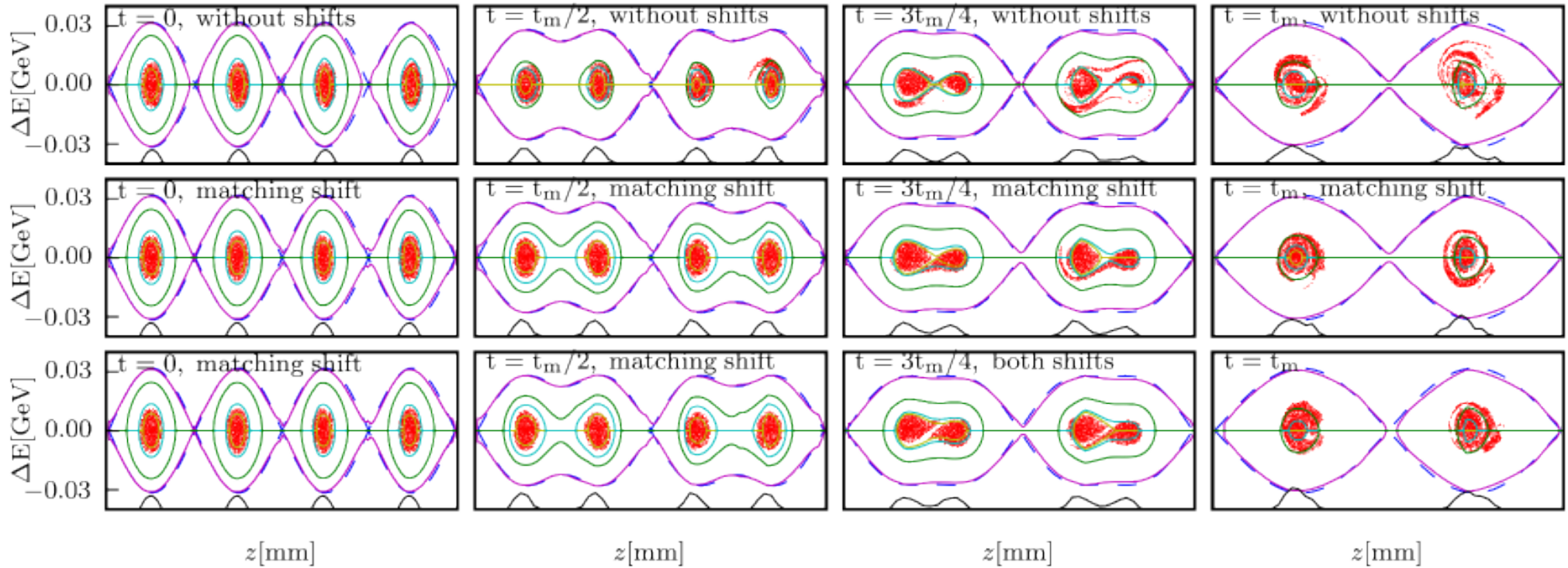
- The **matching shifts** $\Delta\Phi_{bl,i}$ for bunches are different, since the b.l. voltage depends on the positions
- However, $\Delta\Phi_{bl,i}$ break the symmetry during bunch merging
- To compensate the symmetry, the **symmetry shift** $\Delta\Phi_{hf}$ is added on the harmonics (cavities), satisfying

$$\Delta\phi_{hf} = \frac{1}{2}(\Delta\phi_{bl,1} + \Delta\phi_{bl,2})$$

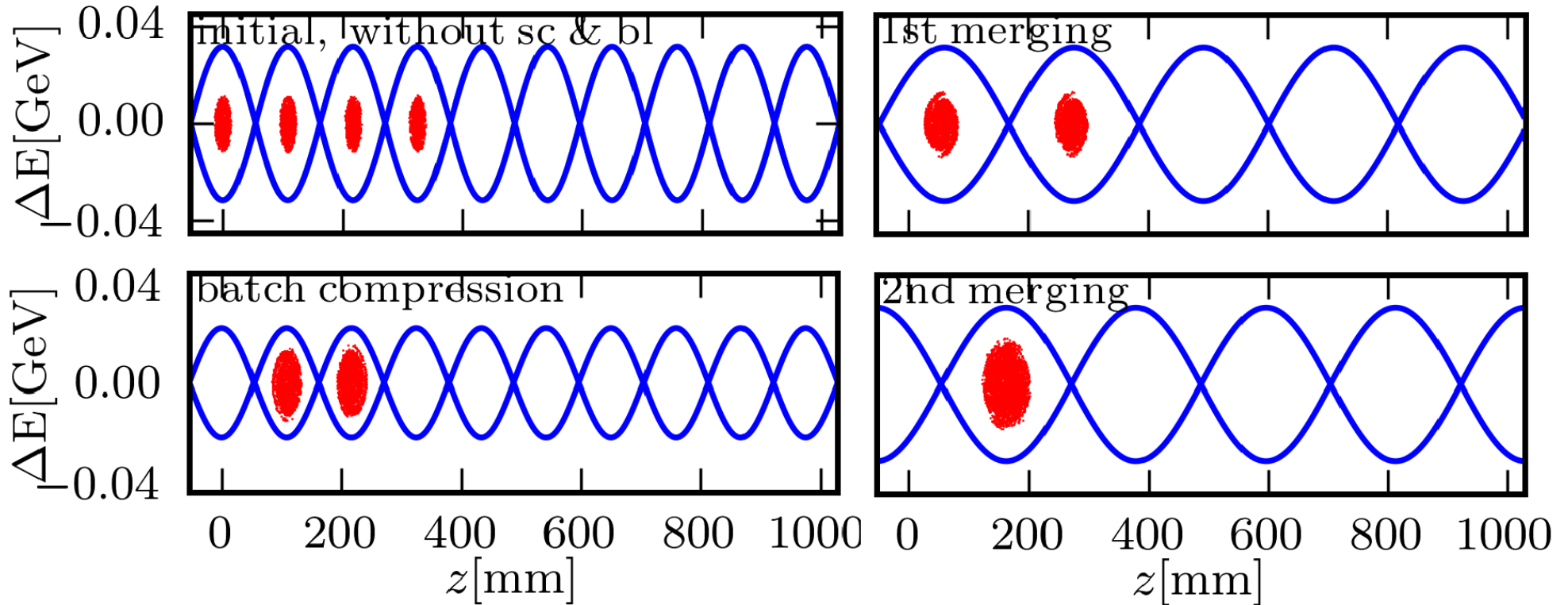
↑
Symmetry shift



Appendix IV Beam loading matching



Appendix V Simulation of proton bunch manipulation without intensity effects



- The emittance growth is $< 3\%$ with total time of 300 ms.
 - 1st bunch merging: 100 ms
 - Batch compression: 100 ms
 - 2nd bunch merging: 100 ms